



IFW
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 9134
Shoriki NARITA et al. : Attorney Docket No. 2001_1718A
Serial No. 09/988,704 : Group Art Unit 2625
Filed November 20, 2001 : Examiner Sheela Chawan

METHOD AND APPARATUS FOR CORRECTING
INCLINATION OF IC ON SEMICONDUCTOR WAFER

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Petition hereby is made for a one month extension of time to respond to the communication of July 27, 2005.

The fee of \$120.00 is

- (X) submitted herewith.
(to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.
 Small entity status of this application is established by a Small Entity Status Assertion which
 is enclosed.
 has been previously submitted.

Respectfully submitted,

Shoriki NARITA et al.

By

W. Douglas Hahn
Registration No. 44,1251
Attorney for Applicant

11/21/2005 JAD001 00000075 09988704

120.00 OP

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November 18, 2005